

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Masaharu Nagai et al. Art Unit : 1795  
Serial No. : 10/694,986 Examiner : Daborah Chacko Davis  
Filed : October 29, 2003 Conf. No. : 5334  
Title : METHOD FOR REMOVING RESIST PATTERN AND METHOD FOR  
MANUFACTURING SEMICONDUCTOR DEVICE

**MAIL STOP AF**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

AMENDMENT IN REPLY TO ACTION OF OCTOBER 8, 2009

Please amend the above-identified application as follows:

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper.

**Remarks/Arguments** begin on page 5 of this paper.